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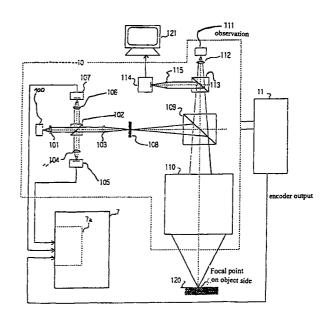
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(54) Proximity exposure device with distance adjustment device

A proximity exposure device with a distance adjustment device in which sufficient determination sensitivity can be obtained even in areas with a low reflectance factor, such as on a glass surface, is achieved by a distance measurement part having a light source (100) for measurement purposes, a pinhole plate (108), an objective lens (110), a light detection device (105) and the like, light emerging form the light source for measurement purposes being emitted via the pinhole plate and objective lens onto the mask surface/workpiece surface (120), and light reflected thereby is detected via the objective lens and pinhole plate by the light detection device. If the mask surface/workpiece surface is located at the focal point of the objective lens on the object side, reflected light with high intensity is incident in the light detection device. To measure the distance between the mask and workpiece, the distance measurement part is moved in the Z-direction and two peaks of intensity of the reflected light of mask M and workpiece W are determined. Based on the position of the distance measurement part at this time, the distance between the mask and workpiece is determined. After measuring the distance between the mask and workpiece, the distance between the mask and workpiece is set to the desired value and exposure is performed.







EUROPEAN SEARCH REPORT

Application Number EP 98 10 5559

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ANNEX TO THE EUROPEAN SEARCH REPORT ON EUROPEAN PATENT APPLICATION NO.

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